

Hiraku Matsukuma

List of Publications by Year in descending order

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26
papers

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citations

759055

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26
all docs

26
docs citations

26
times ranked

321
citing authors

#	ARTICLE	IF	CITATIONS
1	An autocollimator with a mid-infrared laser for angular measurement of rough surfaces. Precision Engineering, 2021, 67, 89-99.	1.8	19
2	A technique for measurement of a prism apex angle by optical angle sensors with a reference artefact. Measurement Science and Technology, 2021, 32, 054007.	1.4	5
3	Self-calibration of a variable-line-spacing grating for an absolute optical encoder with a Fizeau interferometer. Measurement Science and Technology, 2021, 32, 064005.	1.4	6
4	Closed-Loop Control of an XYZ Micro-Stage and Designing of Mechanical Structure for Reduction in Motion Errors. Nanomanufacturing and Metrology, 2021, 4, 53-66.	1.5	10
5	Design and Construction of a Low-Force Stylus Probe for On-machine Tool Cutting Edge Measurement. Nanomanufacturing and Metrology, 2020, 3, 282-291.	1.5	8
6	A differential strategy for measurement of a static force in a single-point diamond cutting by a force-controlled fast tool servo. Measurement Science and Technology, 2020, 31, 074014.	1.4	4
7	Evaluation of the pitch deviation of a linear scale based on a self-calibration method with a Fizeau interferometer. Measurement Science and Technology, 2020, 31, 094002.	1.4	12
8	A new signal processing method for a differential chromatic confocal probe with a mode-locked femtosecond laser. Measurement Science and Technology, 2020, 31, 094004.	1.4	13
9	Reduction in Cross-Talk Errors in a Six-Degree-of-Freedom Surface Encoder. Nanomanufacturing and Metrology, 2019, 2, 111-123.	1.5	26
10	A New Optical Angle Measurement Method Based on Second Harmonic Generation with a Mode-Locked Femtosecond Laser. Nanomanufacturing and Metrology, 2019, 2, 187-198.	1.5	26
11	A chromatic confocal probe with a mode-locked femtosecond laser source. Optics and Laser Technology, 2018, 103, 359-366.	2.2	27
12	A stitching linear-scan method for roundness measurement of small cylinders. CIRP Annals - Manufacturing Technology, 2018, 67, 535-538.	1.7	18
13	Design and Testing of a Micro-thermal Sensor Probe for Nondestructive Detection of Defects on a Flat Surface. Nanomanufacturing and Metrology, 2018, 1, 45-57.	1.5	10
14	The effects of microstructure on propagation of laser-driven radiative heat waves in under-dense high-Z plasma. Physics of Plasmas, 2018, 25, .	0.7	12
15	Uncertainty Evaluation for Measurements of Pitch Deviation and Out-of-Flatness of Planar Scale Gratings by a Fizeau Interferometer in Littrow Configuration. Applied Sciences (Switzerland), 2018, 8, 2539.	1.3	9
16	Uncertainty analysis of a six-degree-of-freedom surface encoder for a planar motion stage. Procedia CIRP, 2018, 75, 355-360.	1.0	1
17	A Liquid-Surface-Based Three-Axis Inclination Sensor for Measurement of Stage Tilt Motions. Sensors, 2018, 18, 398.	2.1	14
18	Actively Q-switched dual-wavelength pumped Er ³⁺ :ZBLAN fiber laser at 347â€‰Åm. Optics Letters, 2018, 43, 2724.	1.7	49

#	ARTICLE	IF	CITATIONS
19	Laser autocollimation based on an optical frequency comb for absolute angular position measurement. Precision Engineering, 2018, 54, 284-293.	1.8	27
20	Error Separation Method for Precision Measurement of the Run-Out of a Microdrill Bit by Using a Laser Scan Micrometer Measurement System. Journal of Manufacturing and Materials Processing, 2018, 2, 4.	1.0	27
21	Far-infrared-light shadowgraphy for high extraction efficiency of extreme ultraviolet light from a CO ₂ -laser-generated tin plasma. Applied Physics Letters, 2016, 109, 051104.	1.5	5
22	The Measurement of Plasma Structure in a Magnetic Thrust Chamber. Plasma and Fusion Research, 2016, 11, 3406012-3406012.	0.3	5
23	Microwave discharge plasma production with resonant cavity for EUV mask inspection tool. Japanese Journal of Applied Physics, 2015, 54, 126701.	0.8	0
24	Correlation between laser absorption and radiation conversion efficiency in laser produced tin plasma. Applied Physics Letters, 2015, 107, 121103.	1.5	13
25	Perturber Dependence of Disalignment Cross Sections of the Argon 2p ₂ Atoms Measured at Temperatures between 77 and 295 K. Journal of the Physical Society of Japan, 2012, 81, 114302.	0.7	3
26	An insight on optical metrology in manufacturing. Measurement Science and Technology, 0, , .	1.4	21